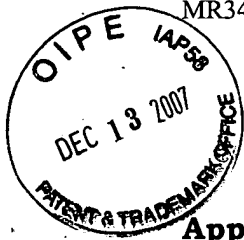


IFW

MR347-44



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No. : 10/674,153
Applicant : KUO-HUANG HSIEH (Inventor)
Filed : September 29, 2003
TC/A.U. : 1762
Examiner : LIN, JAMES

For: Micro-Stamping Method for Photoelectric Process

AMENDMENT AND RESPONSE

Mail Stop Amendment

Honorable Commissioner for Patents

P.O. Box 1450

Alexandria VA 22313-1450

Sir:

The Examiner issued a non-final Office Action dated 14 June 2007 in the above-referenced Patent Application. In the Office Action, the Examiner set a three month shortened statutory period for reply. That reply period having now expired, a Request and fee for a three month Extension of Time is concurrently filed herewith to ensure timely filing.

This paper is in response to the Official Action filed 14 June 2007. Kindly amend the above-identified application as follows:

AMENDMENTS TO THE CLAIMS are reflected in the listing of claims which begins on page 2 of this paper.

REMARKS/ARGUMENTS begin on page 4 of this paper.